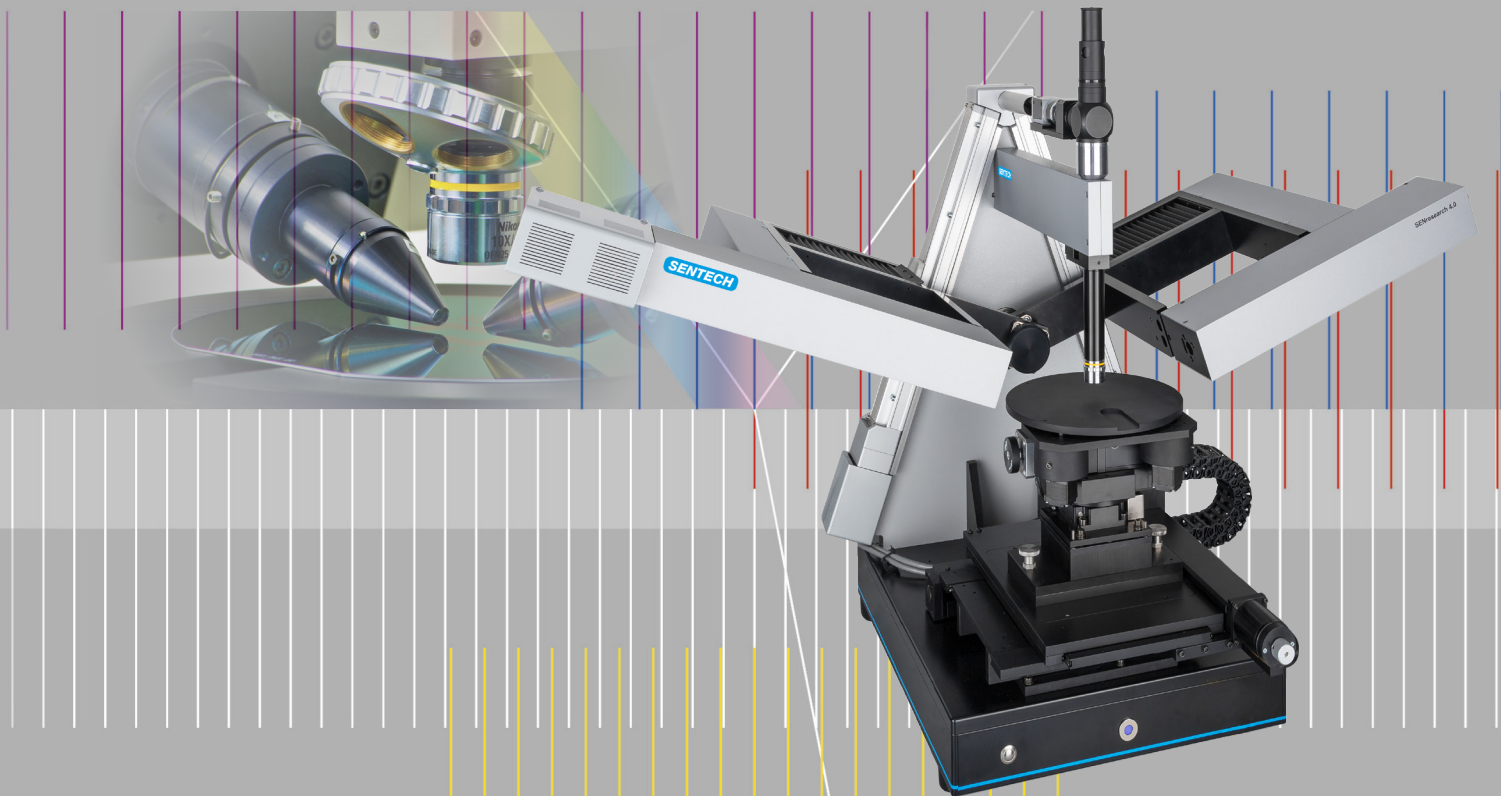


SENTECH equipment for thin film measurement

- Research & development
- Quality control in production
- Photovoltaics
- LEDs & OLEDs



Spectroscopic ellipsometers
Laser ellipsometers
Automated measurement systems
Reflectometers

SENTECH

Erfolg
durch Leistung

Spectroscopic ellipsometers



DUV-VIS-NIR spectroscopic ellipsometer SENresearch 4.0

Large variety of options for R&D and routine applications from DUV to NIR

- Widest spectral range
190 nm (deep UV) – 3,500 nm (NIR)
- No moving parts with SSA principle
- Full Mueller matrix by innovative 2 C design
- Comprehensive ellipsometry software
SpectraRay/4



Cost-effective ellipsometer SENpro

Focused on speed and accuracy for the measurement of thin films (1 nm to 15 µm)

- Spectral range 370–1,050 nm
- Goniometer with preset angles of incidence
- Step Scan Analyzer principle for highest measurement accuracy
- Comprehensive ellipsometry software
SpectraRay/4

Infrared spectroscopic ellipsometer SENDIRA

Vibrational spectroscopic analysis of thin layers (dielectric layers, TCOs, semiconductors, organic layers)

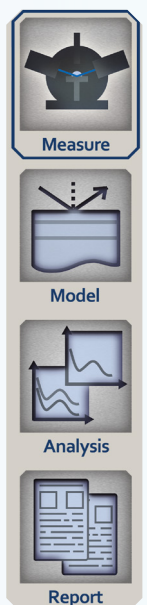
- IR spectral range 1,700–25,000 nm
- Fully applicable FTIR spectrometer
- Comprehensive ellipsometry software
SpectraRay/4



Spectroscopic ellipsometer software SpectraRay/4

User-friendly software with recipe oriented mode for operators and advanced mode for interactive measurement and modeling

- Supports variable angle, multi-experiment, and combined photometric measurements
- Ellipsometric, reflection, and transmission data
- Huge library of materials' data, large number of dispersion models
- Sample effects: depolarization, non-uniformity, scattering (Mueller-matrix), backside reflection



Laser ellipsometers



Multiple angle laser ellipsometer SE 400adv

Characterization of single films and substrates in microelectronic, photovoltaic, data storage, display technology, life science, metal processing, etc.

- Application specific angles of incidence
- HeNe laser of 632.8nm wavelength
- Measurement precision of 0.1 Å
- High measurement speed allows for film growth monitoring and endpoint detection



Combined Ellipsometry Reflectometry SE 500adv

Maximum flexibility for the analysis of thick dielectric, organic, photoresist, silicon, or polysilicon films

- Fast and unambiguous determination of the thickness of transparent films up to 25µm
- Multiple angle manual goniometer for the characterization of single films and layer stacks

Automated measurement tools

Automated ellipsometer for R&D SENDURO

Fast, highly precise, and repeatable measurements in production, process monitoring, and R&D

- Spectral range 290–850nm
- Patented automatic alignment sensors
- Step Scan Analyzer principle for highest measurement accuracy
- Small footprint
- Routine applications
- Comprehensive ellipsometry software **SpectraRay/4**



Ellipsometer for routine applications SENDURO® MEMS

Metrology platform for MEMS applications

- Measurement of film thickness and refractive index
- Cassette loading up to 8" wafers
- Edge grip wafer handling
- Pattern recognition
- SECS/GEM interface



Reflectometers



Spectroscopic reflectometer RM 1000/2000

Accurate measurements of reflectance, film thickness, and optical constants of films between 5nm and 50µm

- Small spot size
- UV to NIR spectral range
- Most accurate measurement by height and tilt adjustment of samples
- Optional high resolution mapping
- Comprehensive, recipe-oriented reflectometer software **FTPadv EXPERT**

Film Thickness Probe FTPadv

Fast and easy measurement of film thickness in production, process monitoring, and R&D



- Thickness range 30 nm – 25 µm
- Recipe oriented software
- Adaptation to a microscope for measurements in small areas

Summary

	Thickness of single film	Thickness of films < 5 nm	Thickness of films > 20 µm	Analysis of layer stack	n, k	Dispersion of n, k	Band gap	Composition	Uniformity	Conductivity	Crystallinity (order)	Roughness	Impurities	Epiayers	Anisotropy	Material gradients
SE 400adv	✓	✓			✓			(✓)	✓			✓			✓	
SE 500adv	✓	✓	✓		✓	(✓)		(✓)	✓			✓			✓	
SENpro	✓	✓		✓	✓	✓	✓	✓	✓		✓	✓			✓	✓
SENresearch 4.0	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓			✓	✓
SENDIRA	✓	(✓)	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	✓	(✓)	✓
SENDURO	✓	✓		✓	✓	✓	✓	✓	✓		✓	✓				
RM 1000/ RM 2000	✓		✓	(✓)	✓	✓	(✓)	(✓)	✓							
FTPadv	✓		✓						(✓)							

(✓) only in special applications

Please consult also our brochures about thin film metrology for crystalline silicon and thin film solar cells.

SENTECH Instruments GmbH
Schwarzschildstr. 2
12489 Berlin, Germany
Tel: +49 30 6392 5520
Fax: +49 30 6392 5522
E-mail: marketing@sentech.de
www.sentech.com

SENTECH Gesellschaft für Sensortechnik mbH
Konrad-Zuse-Bogen 13
82152 Krailling/KIM, Germany
Tel: +49 89 897 9607 0
Fax: +49 89 897 9607 22
E-mail: sales@sentech.de
www.sentech-sales.de



Erfolg
durch Leistung